

# *Integrated MEMS Mechanical Shock Sensor*

## *NSWC Indian Head*



NDIA Fuze  
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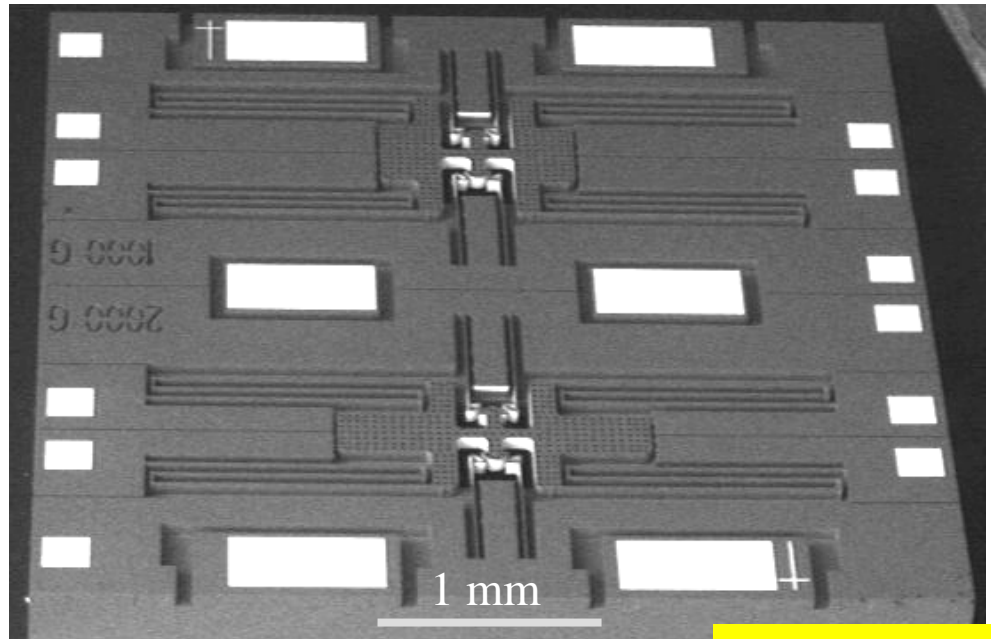
Naval Surface Warfare Center  
Indian Head, MD USA





# Outline

- Overview
- Applications
  - Integrated shock sensor for S&A
  - Stand alone shock and impact switch
- Modeling
- Packaging
- Testing
- Advanced Designs
- Future Applications



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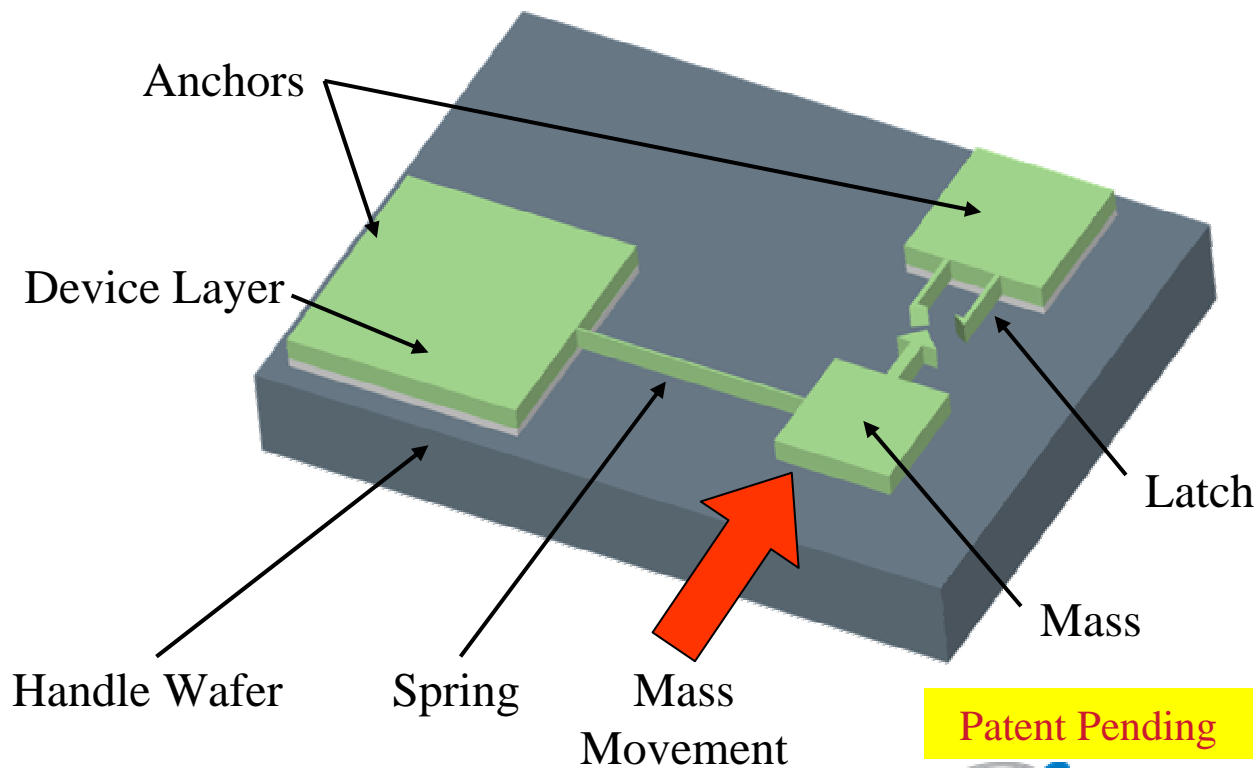


# Shock Sensor Overview

- A non-powered shock sensor that latches if the applied shock is above a predetermined threshold

Threshold Sensor:

- Impact and shock
- Mass Moves
- Latch engages



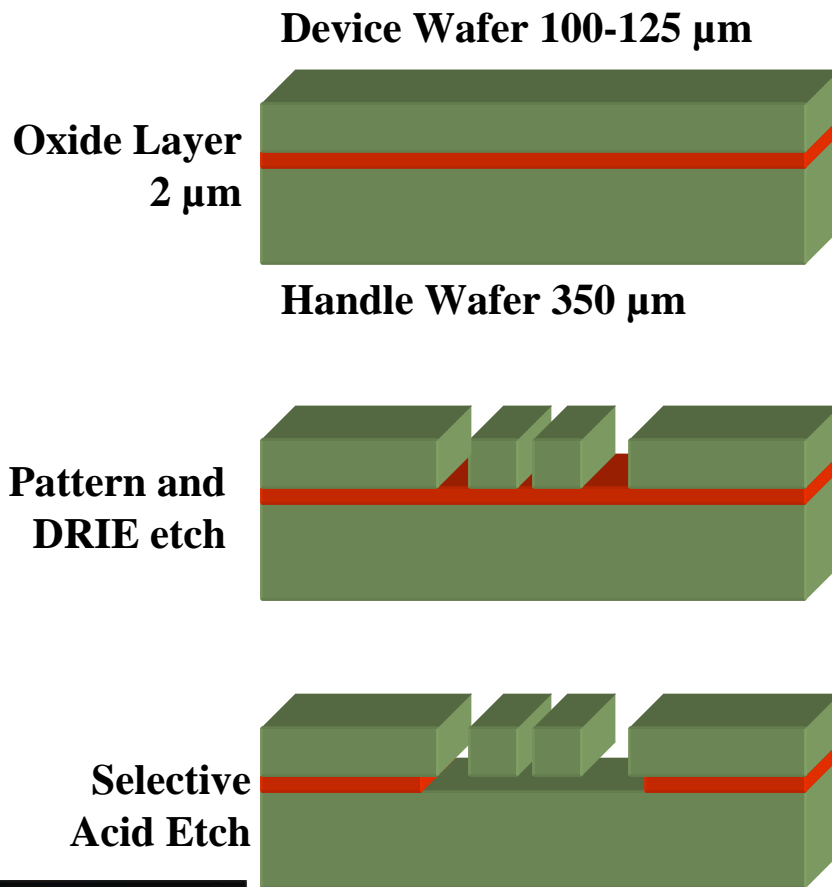
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# Fabrication: DRIE

- Deep Reactive Ion Etching (DRIE) using Silicon on Insulator (SOI) wafers



Process Flow:

1. Begin with SOI wafer
2. Pattern device wafer
3. DRIE etch to oxide stop
4. Partial release in timed acid etch
  - large structures = anchored
  - small structures = released

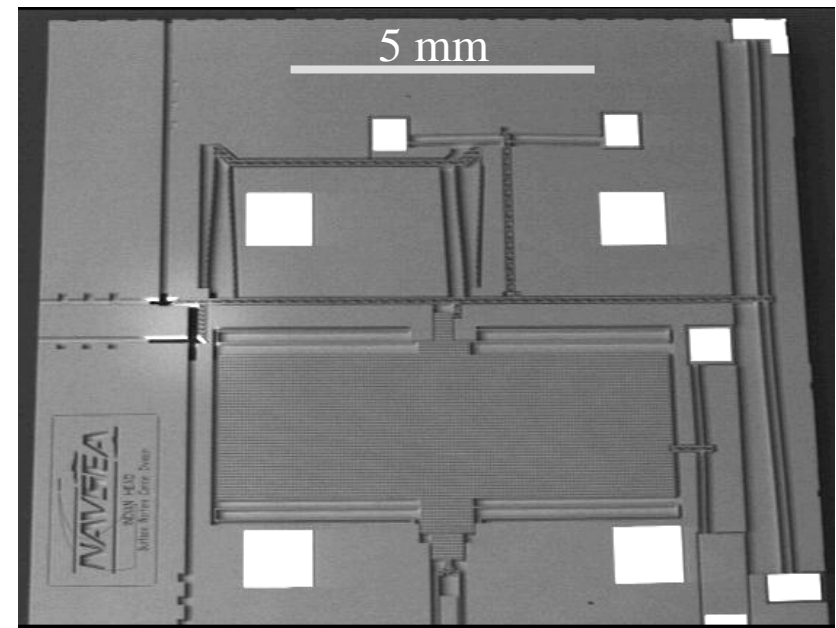
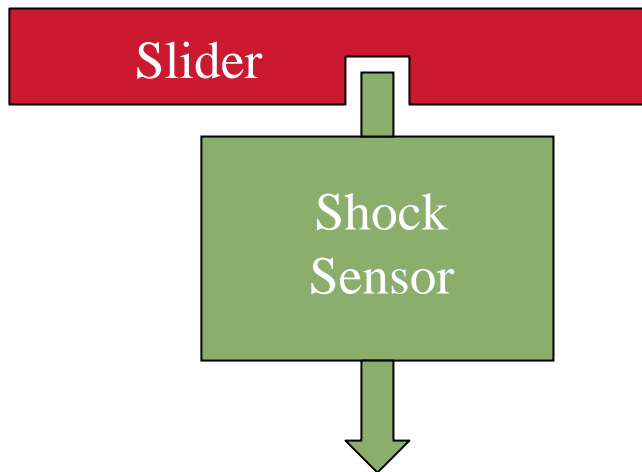
Commercial DRIE:

- Accelerometers, IMUs
- Pressure and Chemical Sensors
- Over 10 commercial and 40 academic foundries



# *Integrated Shock Sensor for S&A*

- Mass locks a slider
- Lock is removed when the shock exceeds the designed threshold
- Used as an environmental sensor on the Canistered Countermeasure Anti-Torpedo (CCAT) S&A

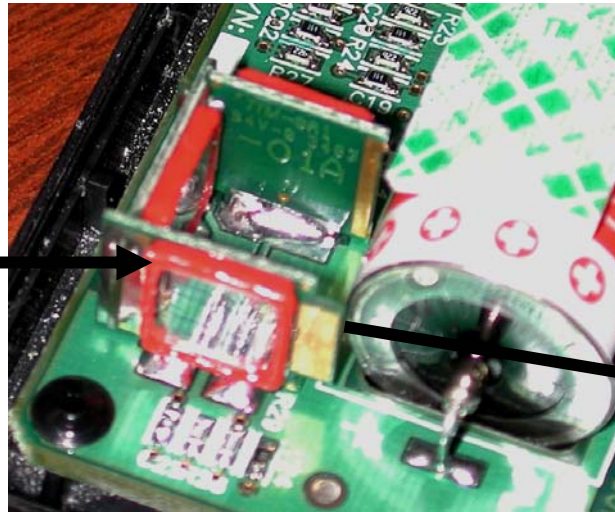
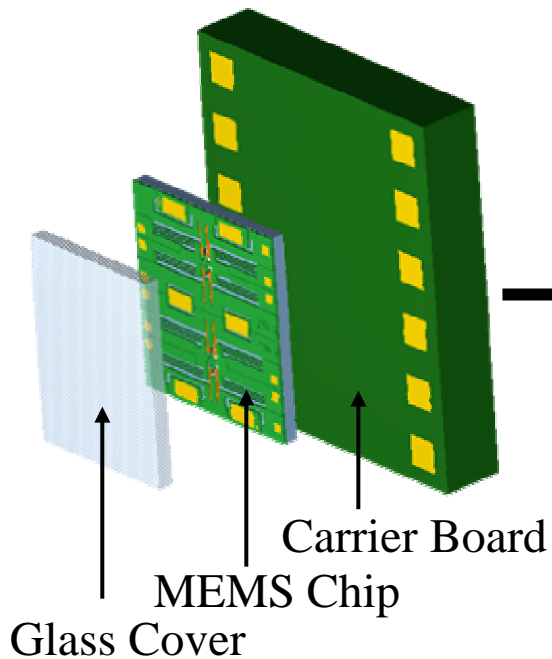


12 by 12 mm CCAT S&A Chip



# Stand-Alone Shock and Impact Sensor ATOS RFID Tag

- Mass closes an electrical switch when the shock threshold is exceeded
- Used in the Advanced Technology Ordnance Surveillance Radio Frequency Identification (ATOS RFID)



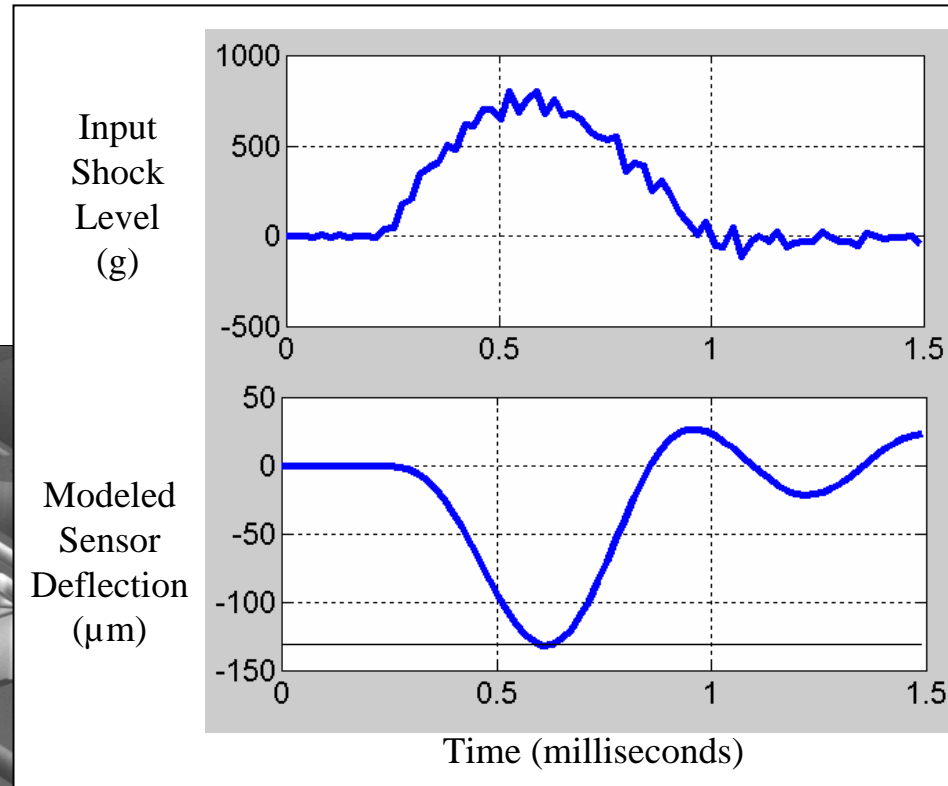
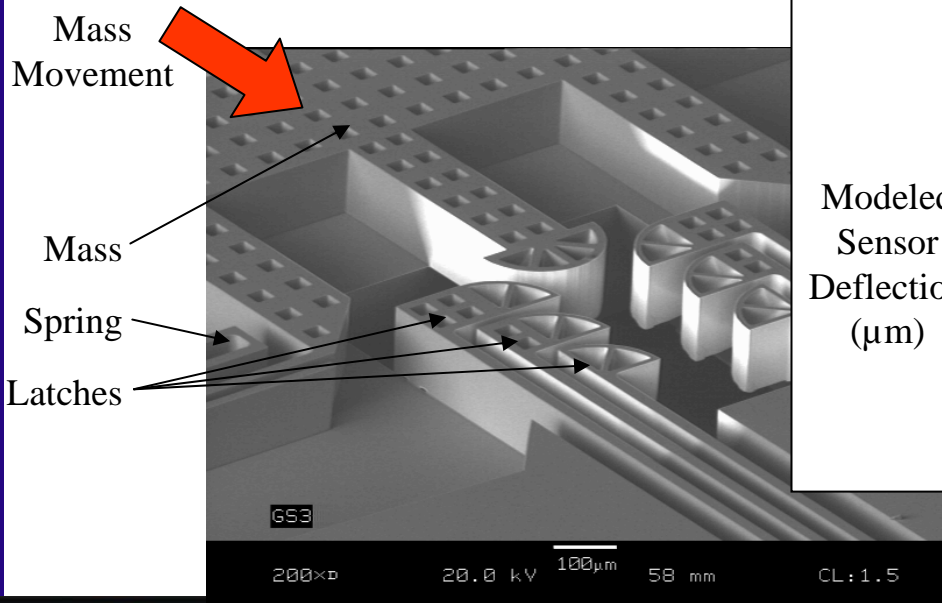


# Modeling

- Used to predict latching levels
- Using vibration equation for base excitation:

$$m\ddot{z} + c\dot{z} + kz = -m\ddot{y}$$

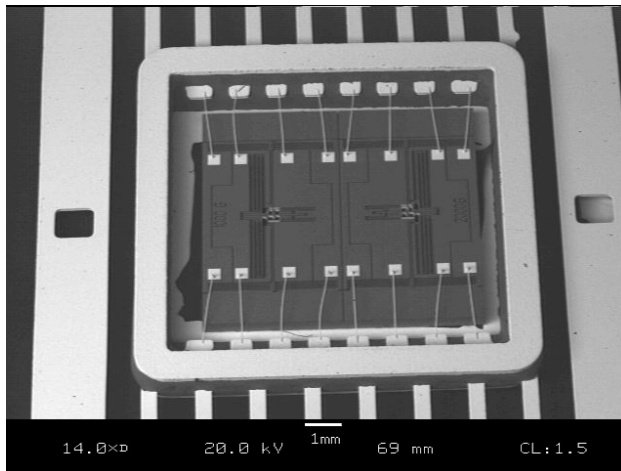
- Solved using 2 separate techniques:
  - Duhamel integral
  - Finite difference



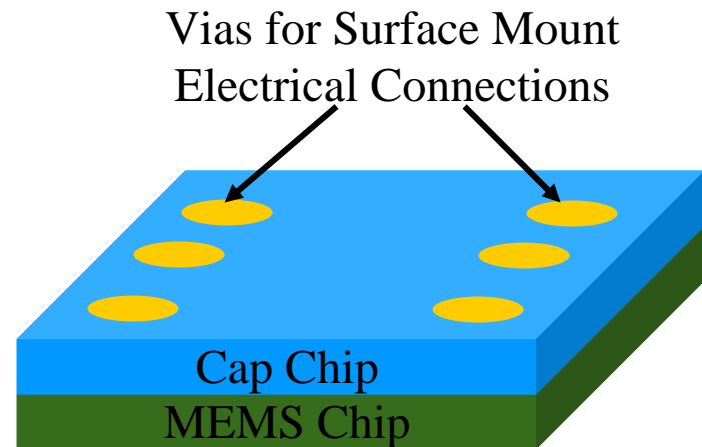


# Packaging

- Cap chip to limit out-of-plane deflection
- Hermetic packaging is necessary for long shelf life applications
- Packaging options
  - Hermetic chip carrier: current technology
  - Chip level hermetic seal: future for low cost and high volume



Hermetic Chip Carrier



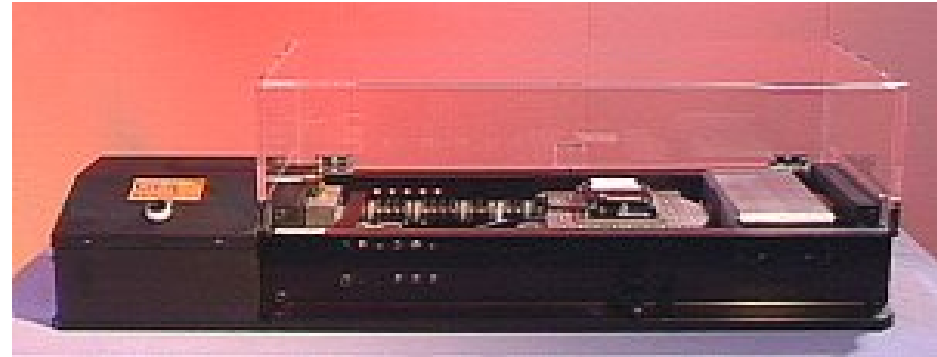
Chip-Level Hermetic Seal



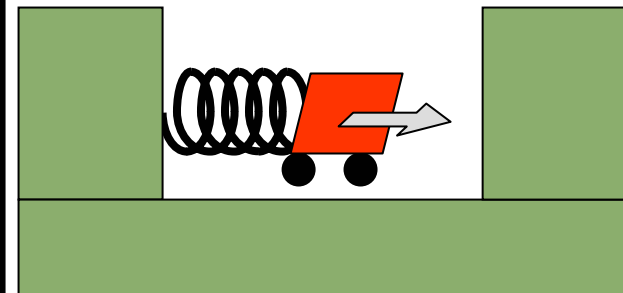


# Initial Shock Testing

- Using a linear shock table



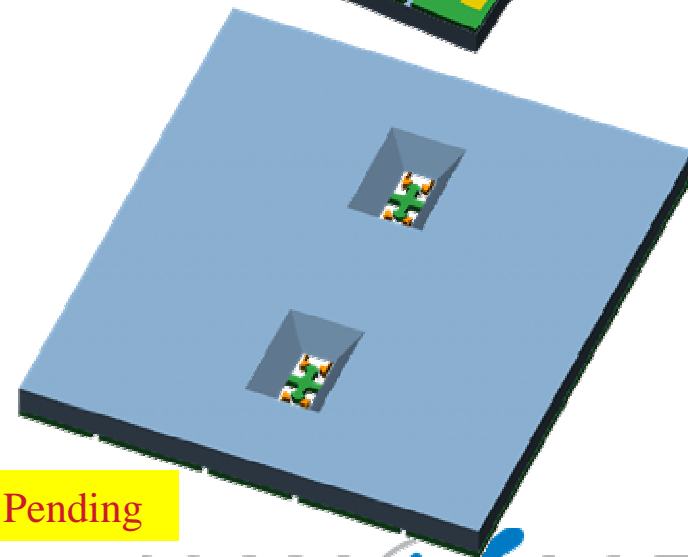
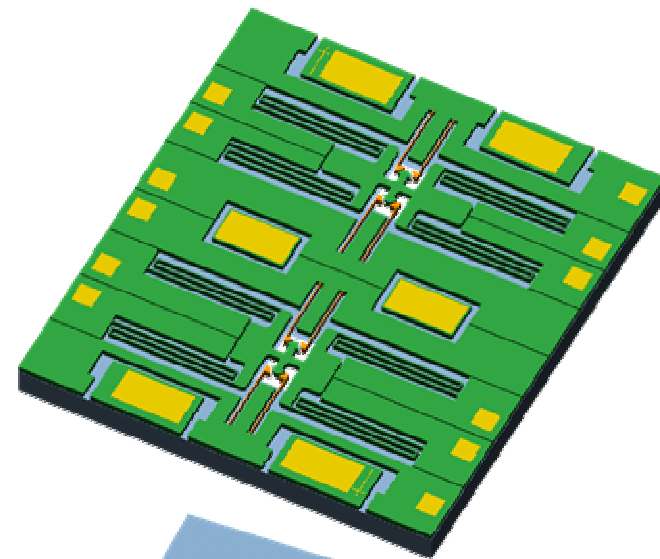
Sensor Design	Average Latch Level (g)	Range	Number Tested
1	199	$\pm 1\%$	2
2	390	$\pm 3\%$	5
3	527	$\pm 2\%$	5
4	712	$\pm 4\%$	4
5	1064	$\pm 2\%$	2





# 5" Airgun High Shock Testing

- Primarily to demonstrate survivability
- Sensors: 6.2 by 6.7 mm
  - Two sensors per chip designed to latch at 360 and 720 G, tested at 30 kG
- Using existing hardware not designed for high shock survivability:
  - Large mass
  - Etched square holes in substrate



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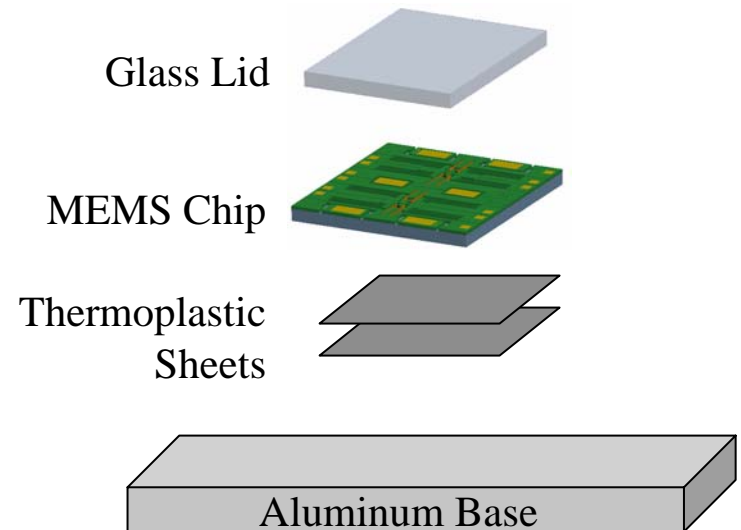


# Shock Survivability Packaging

- Glass lid attachment with solder (and flux)
- MEMS chip attachment with two 5 mil thermoplastic sheets
- Epoxy reinforcement of glass lid
- 22 packages were made



0.80 in



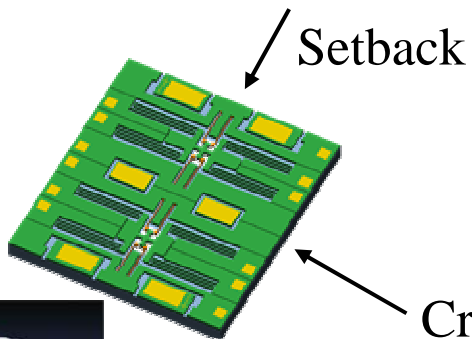
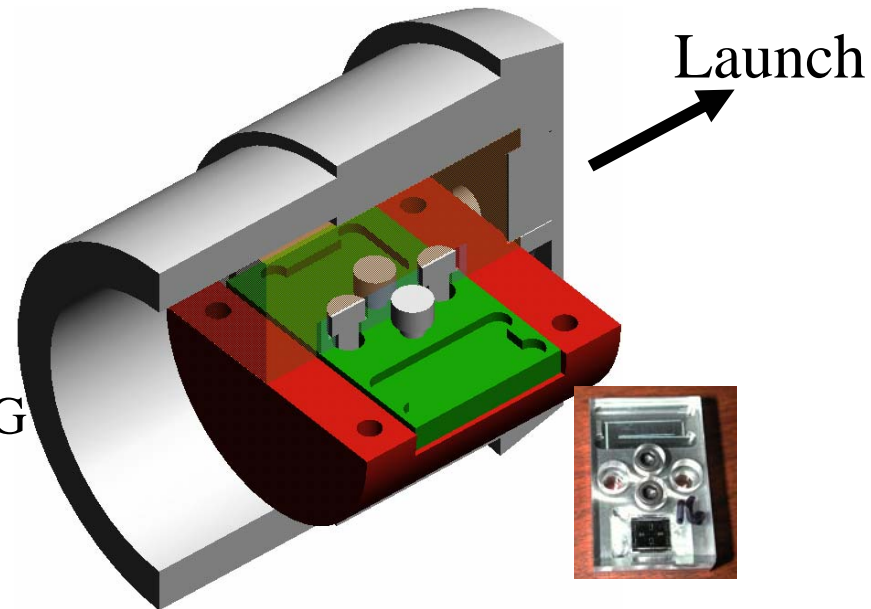


# 5" Airgun Test Levels

- Setback testing: 14 tests from 1,450 G to 29,900 G
  - Tests conducted using 5" airgun at NSWC Dahlgren
  - One test at each of the following levels

1,450	9,230	26,240
1,470	14,140	27,210
6,380	14,700	28,110
6,840	14,800	29,900
8,340	15,390	

- Cross-axis testing
  - 2 tests at 23,000 G and 28,700 G



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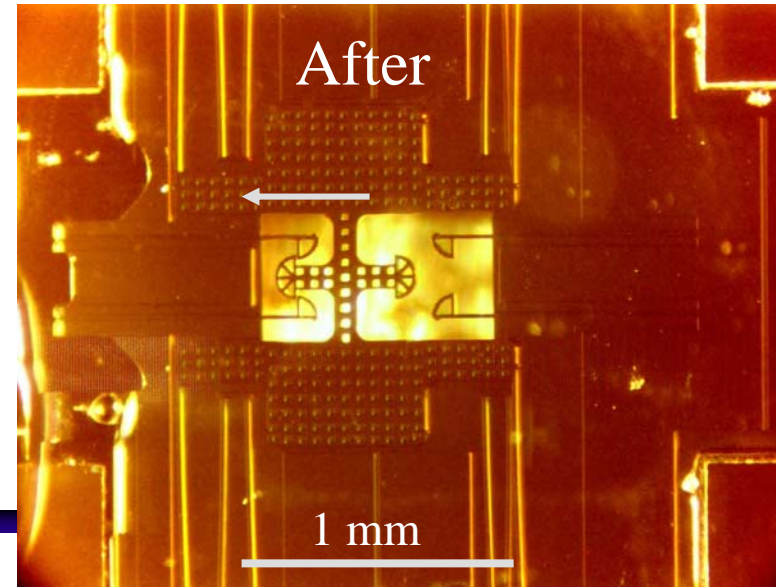
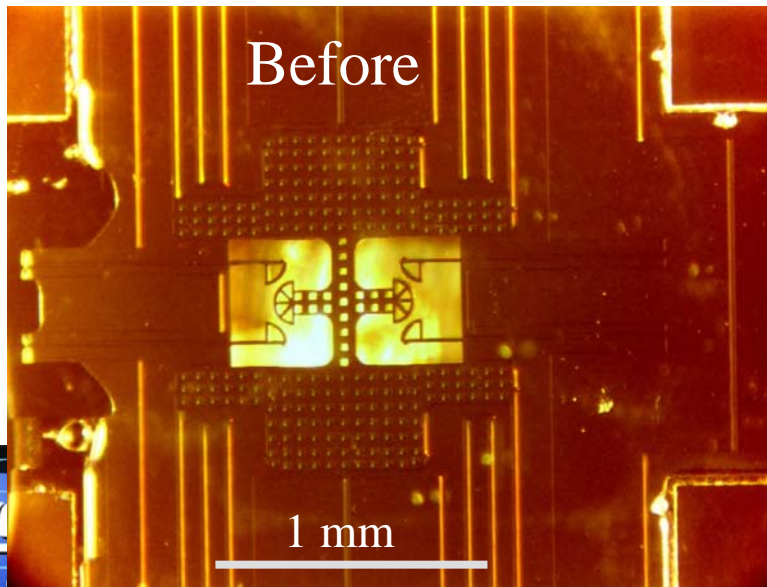




# 5" Airgun Test Results

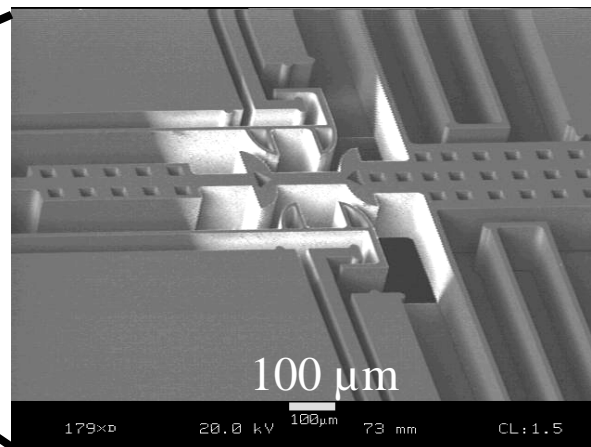
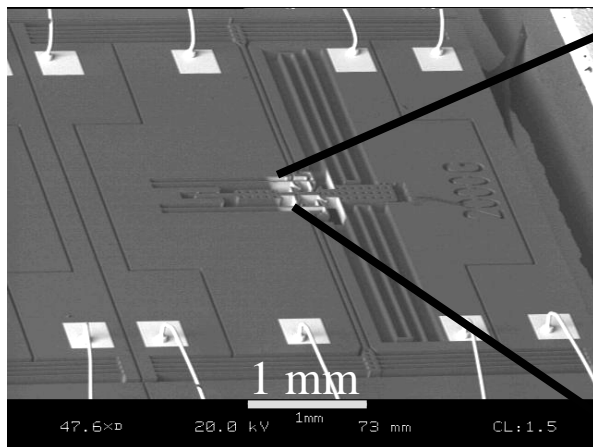
- 27 out of 27 sensors functioned as designed (1 no-test, sensor damaged during packaging)
- No observable damage to the substrate
- Below 25,000 G: 1 broken latch out of 96 latches, most likely due to the etch pit under the latch
- Between 25,000 and 30,000 G:
  - 1 broken mass out of 10
  - 5 broken springs out of 40
  - 2 broken latches out of 40

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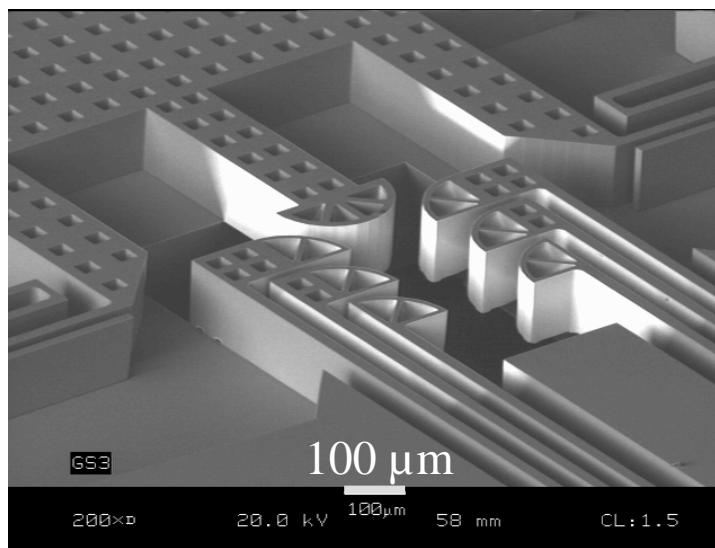




# Advanced Sensor Designs



Releasable



Multi-Level

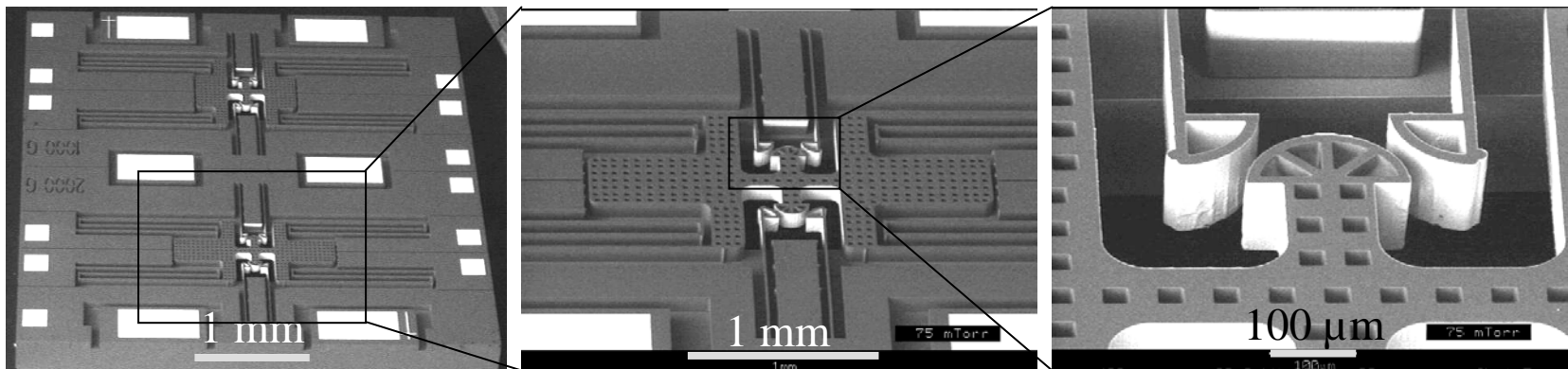
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# *Future Applications*

- DRIE silicon MEMS technology is applicable to explosive-on-a-slider for high-g fuze/S&A applications
- Next-generation medium caliber gun launched munitions
- Submunitions

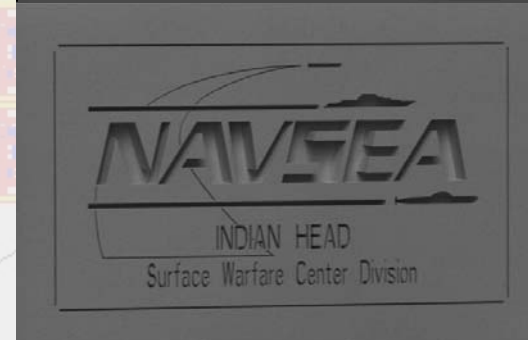


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# Conclusion

- Shock Sensor
  - Over 1000 working sensors fabricated to date
  - Accurate sensors fabricated from 30 to 1100 g
  - Shock survivability demonstrated to 30,000 g
- Current applications
  - Integrated into S&A for CCAT
  - Stand alone sensor for ATOS
- Future applications
  - Med. caliber gun-launched munitions
  - Submunitions







# Acknowledgements

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